

<<表面和薄膜过程导论>>

图书基本信息

书名：<<表面和薄膜过程导论>>

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内容概要

表面和薄膜科学是微电子、光电子和磁工业的物理基础，是现代社会技术进步的科学保证。在微观以至原子水平上研究和操纵表面让我们能够理解许多具有重要技术意义之器件的制作与运行。《表面和薄膜过程导论（第4版）》关注发生在表面和薄膜中的物理过程，详细介绍了与表面和薄膜相关的物理过程，包括热力学与运动学的理论基础，洁净表面的制备和表面的表征与分析技术，表面吸附与脱附过程，金属和半导体表面性质，外延生长和薄膜器件的表面过程等等内容。

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书籍目录

Preface
Chapter 1 Introduction to surface processes
1.1 Elementary thermodynamic ideas of surfaces
1.2 Surface energies and the Wulff theorem
1.3 Thermodynamics versus kinetics
1.4 Introduction to surface and adsorbate reconstructions
1.5 Introduction to surface electronics
Further reading for chapter 1
Problems for chapter 1
Chapter 2 Surfaces in vacuum ultra-high vacuum techniques and processes
2.1 Kinetic theory concepts
2.2 Vacuum concepts
2.3 UHV hardware: pumps, tubes, materials and pressure measurement
2.4 Surface preparation and cleaning procedures in situ experiments
2.5 Thin film deposition procedures: sources of information
Further reading for chapter 2
Problems for chapter 2
Chapter 3 Electron-based techniques for examining surface and thin film processes
3.1 Classification of surface and microscopy techniques
3.2 Diffraction and quasi-elastic scattering techniques
3.3 Inelastic scattering techniques; chemical and electronic state information
3.4 Quantification of Auger spectra
3.5 Microscopy-spectroscopy SEM SAM SPM etc.
Further reading for chapter 3
Problems, talks and projects for chapter 3
Chapter 4 Surface processes in adsorption
Chapter 5 Surface processes in epitaxial growth
Chapter 6 Electronic structure and processes at metallic surfaces
Chapter 7 Semiconductor surfaces and interfaces
Chapter 8 Surface processes in thin film devices
Chapter 9 Postscript - where do we go from here?
References
Index

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